## Taehwan Moon

List of Publications by Year in descending order

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186265 330143 4,156 37 28 37 h-index citations g-index papers 37 37 37 2330 docs citations times ranked citing authors all docs

#	Article	IF	CITATIONS
1	Ferroelectricity and Antiferroelectricity of Doped Thin HfO <sub>2</sub> â€Based Films. Advanced Materials, 2015, 27, 1811-1831.	21.0	777
2	Evolution of phases and ferroelectric properties of thin Hf0.5Zr0.5O2 films according to the thickness and annealing temperature. Applied Physics Letters, 2013, $102$ , .	3.3	480
3	Thin Hf <sub><i>x</i></sub> Zr <sub>1â€<i>x</i></sub> O <sub>2</sub> Films: A New Leadâ€Free System for Electrostatic Supercapacitors with Large Energy Storage Density and Robust Thermal Stability. Advanced Energy Materials, 2014, 4, 1400610.	19.5	286
4	The effects of crystallographic orientation and strain of thin Hf0.5Zr0.5O2 film on its ferroelectricity. Applied Physics Letters, 2014, 104, .	3.3	268
5	A study on the wake-up effect of ferroelectric Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> films by pulse-switching measurement. Nanoscale, 2016, 8, 1383-1389.	5.6	195
6	Grain size engineering for ferroelectric Hf0.5Zr0.5O2 films by an insertion of Al2O3 interlayer. Applied Physics Letters, 2014, 105, .	3.3	187
7	Toward a multifunctional monolithic device based on pyroelectricity and the electrocaloric effect of thin antiferroelectric Hf x Zr $1\hat{a}$ °x O 2 films. Nano Energy, 2015, 12, 131-140.	16.0	174
8	Effect of Zr Content on the Wake-Up Effect in Hf <sub>1â€"<i>x</i>xxxxxxx&lt;</sub>	8.0	172
9	Understanding the formation of the metastable ferroelectric phase in hafnia–zirconia solid solution thin films. Nanoscale, 2018, 10, 716-725.	5.6	159
10	Study on the degradation mechanism of the ferroelectric properties of thin Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> films on TiN and Ir electrodes. Applied Physics Letters, 2014, 105, 072902.	3.3	133
11	Ferroelectric properties and switching endurance of Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> films on TiN bottom and TiN or RuO <sub>2</sub> top electrodes. Physica Status Solidi - Rapid Research Letters, 2014, 8, 532-535.	2.4	131
12	Study on the size effect in Hf0.5Zr0.5O2 films thinner than 8 nm before and after wake-up field cycling. Applied Physics Letters, 2015, 107, .	3.3	124
13	Giant Negative Electrocaloric Effects of Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> Thin Films. Advanced Materials, 2016, 28, 7956-7961.	21.0	115
14	Scale-up and optimization of HfO2-ZrO2 solid solution thin films for the electrostatic supercapacitors. Nano Energy, 2017, 39, 390-399.	16.0	87
15	Time-Dependent Negative Capacitance Effects in Al <sub>2</sub> O <sub>3</sub> /BaTiO <sub>3</sub> Bilayers. Nano Letters, 2016, 16, 4375-4381.	9.1	75
16	Preparation and characterization of ferroelectric Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> thin films grown by reactive sputtering. Nanotechnology, 2017, 28, 305703.	2.6	75
17	A comprehensive study on the mechanism of ferroelectric phase formation in hafnia-zirconia nanolaminates and superlattices. Applied Physics Reviews, 2019, 6, .	11.3	73
18	Morphotropic Phase Boundary of Hf <sub>1–<i>×</i></sub> Zr <sub><i>×</i></sub> O <sub>2</sub> Thin Films for Dynamic Random Access Memories. ACS Applied Materials & Therfaces, 2018, 10, 42666-42673.	8.0	68

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19	Voltage Drop in a Ferroelectric Single Layer Capacitor by Retarded Domain Nucleation. Nano Letters, 2017, 17, 7796-7802.	9.1	66
20	Dispersion in Ferroelectric Switching Performance of Polycrystalline Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> Thin Films. ACS Applied Materials & Interfaces, 2018, 10, 35374-35384.	8.0	55
21	Nucleationâ€Limited Ferroelectric Orthorhombic Phase Formation in Hf <sub>0.5</sub> Zr <sub>0.5</sub> O <sub>2</sub> Thin Films. Advanced Electronic Materials, 2019, 5, 1800436.	5.1	55
22	Transient Negative Capacitance Effect in Atomicâ€Layerâ€Deposited Al <sub>2</sub> O <sub>3</sub> /Hf <sub>0.3</sub> Zr <sub>0.7</sub> O <sub>2</sub> Bilayer Thin Film. Advanced Functional Materials, 2019, 29, 1808228.	14.9	47
23	Frustration of Negative Capacitance in Al2O3/BaTiO3 Bilayer Structure. Scientific Reports, 2016, 6, 19039.	3.3	44
24	Two-step polarization switching mediated by a nonpolar intermediate phase in Hf <sub>0.4</sub> Zr <sub>0.6</sub> O <sub>2</sub> thin films. Nanoscale, 2016, 8, 13898-13907.	5.6	44
25	Alternative interpretations for decreasing voltage with increasing charge in ferroelectric capacitors. Scientific Reports, 2016, 6, 20825.	3.3	43
26	Unexpectedly low barrier of ferroelectric switching in HfO2 via topological domain walls. Materials Today, 2021, 50, 8-15.	14.2	40
27	A Comparative Study on the Ferroelectric Performances in Atomic Layer Deposited Hf0.5Zr0.5O2 Thin Films Using Tetrakis(ethylmethylamino) and Tetrakis(dimethylamino) Precursors. Nanoscale Research Letters, 2020, 15, 72.	5.7	38
28	Interfacial charge-induced polarization switching in Al2O3/Pb(Zr,Ti)O3 bi-layer. Journal of Applied Physics, 2015, 118, .	2.5	30
29	Unveiling the Origin of Robust Ferroelectricity in Sub-2 nm Hafnium Zirconium Oxide Films. ACS Applied Materials & Diterfaces, 2021, 13, 36499-36506.	8.0	24
30	Effect of the annealing temperature of thin Hf <sub>0.3</sub> Zr <sub>0.7</sub> O <sub>2</sub> films on their energy storage behavior. Physica Status Solidi - Rapid Research Letters, 2014, 8, 857-861.	2.4	19
31	2D Electron Gas at the Interface of Atomicâ€Layerâ€Deposited Al <sub>2</sub> O <sub>3</sub> /TiO <sub>2</sub> on SrTiO <sub>3</sub> Single Crystal Substrate. Advanced Electronic Materials, 2019, 5, 1800527.	5.1	18
32	Composition, Microstructure, and Electrical Performance of Sputtered SnO Thin Films for p-Type Oxide Semiconductor. ACS Applied Materials & Samp; Interfaces, 2018, 10, 3810-3821.	8.0	16
33	Research Update: Diode performance of the Pt/Al2O3/two-dimensional electron gas/SrTiO3 structure and its time-dependent resistance evolution. APL Materials, 2017, 5, .	5.1	8
34	Origin of the Threshold Voltage Shift in a Transistor with a 2D Electron Gas Channel at the Al 2 O 3 /SrTiO 3 Interface. Advanced Electronic Materials, 2020, 6, 1901286.	5.1	8
35	Characterization of a 2D Electron Gas at the Interface of Atomicâ€Layer Deposited Al 2 O 3 /ZnO Thin Films for a Fieldâ€Effect Transistor. Advanced Electronic Materials, 2021, 7, 2000876.	5.1	8
36	Diode Property and Positive Temperature Coefficient of Resistance of Pt/Al <sub>2</sub> O <sub>3</sub> /Nb:SrTiO <sub>3</sub> . Advanced Electronic Materials, 2018, 4, 1800388.	5.1	7

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37	Threshold Voltage Modulation in a Transistor with a Two-Dimensional Electron Gas Channel at the Interface between Al <sub>2</sub> O <sub>3</sub> and Sub-5 nm ZnO Films. ACS Applied Electronic Materials, 2021, 3, 3247-3255.	4.3	7